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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Applicant of: Mamoru NAKASUJI et al.

Serial Number: 09/891,511

Group Art Unit: 2812

Filed: June 27, 2001

Examiner: Unassigned



INSPECTION SYSTEM BY CHARGED PARTICLE BEAM AND METHOD OF
MANUFACTURING DEVICES USING THE SYSTEM

INFORMATION DISCLOSURE STATEMENT
PURSUANT TO 37 CFR 1.97(b)

Commissioner for Patents
Washington, D.C. 20231

January 18, 2002

Sir:

The attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached Form PTO-1449. One copy of each of these documents is attached.

No fee or certification is required in connection with this Information Disclosure Statement, since it is being submitted prior to the issuance of a first official action on the merits or expiration of the three month period following the filing date or the entry of the national stage of the above-captioned application.

The above information is presented so that the Patent and Trademark Office can, in the first instance, determine any materiality thereof to the claimed invention. See 37 CFR 1.104(a) concerning the PTO duty to consider and use any such information. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the documents cited in the attached Form PTO-1449 be made of record therein and appear on the first page of any patent to issue therefrom.

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Serial No.: 09/891,511
Applicant: Mamoru NAKASUJI et al.

Attorney Docket No. 010819
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The Commissioner is authorized to charge our Deposit Account No. 01-2340 for any fee which is deemed by the Patent and Trademark Office to be required to effect consideration of this statement.

Respectfully submitted,

ARMSTRONG, WESTERMAN & HATTORI, LLP




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Enclosures: European Search Report
PTO-1449 w/ 41 References

INFORMATION DISCLOSURE CITATION PTO-1449	Atty. Docket No. 010819	Serial No. 09/891,511
	Applicant: Mamoru NAKASUJI et al.	
	Filing Date: June 27, 2001	Group Art Unit: 2812

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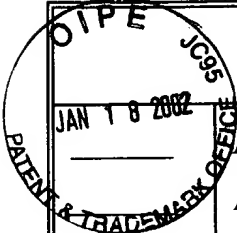
Examiner Initials	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
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	BJ	<i>Low Voltage and high speed operating electrostatic wafer chuck using sputtered tantalum oxide membrane</i> , Mamoru Nakasuji et al., J. Vac. Sci. Technol. A 12(5), Sep/Oct 1994, American Vacuum Society pp. 2834-2839.
	BK	<i>High -Emittance and Low-Brightness Electron Gun for Reducing-Image Projection System: Computer Simulation</i> , Mamoru Nakasuji et al., Jpn. J. Appl. Phys. Vol. 36 (1997) pp.2404-2408.
	BL	H. Hayashi, et al., <i>LSI Testing Symposium 1998, Minutes of the meeting</i> , P160 (1998) (partial translation)

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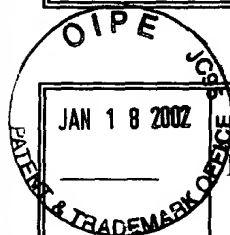


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Examiner	Date Considered
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_____	BP	<i>Table 5-1 Work Function in Metals</i> page 116.
_____	BQ	
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